

3D Optical Profilers

Objective Lenses Specifications



Objective Lenses Specifications

The S neox and S neox Five Axis systems use premium CF60-2 Nikon objectives lenses that have been designed to correct chromatic aberrations and produce sharp, flat and clear images with high contrast and high resolution. Phase Fresnel lenses improve the operability and the working distance, meaning that S line objectives provide the largest available working distance for each NA.

The S line also uses interferometric objectives. The TI series are based on Michelson interferometer. They have an external reference mirror mounted on two tip-tilt screws. The DI series are Mirau objectives that creates the interference internally by dividing the wavefront with a beamsplitter. The TI series are used for low magnification and numerical aperture, being ideal objectives for the measurement of very flat at and thin samples. The DI series can have up to 0.55NA.

Bright field objective lenses

Magnification	NA	WD (mm)	FOV (μm)	Spatial Sampling (μm)	Optical Resolution Green (μm)	Optical Resolution Blue (μm)	Optical Resolution Red (μm)	Optical Resolution White (μm)	Maximum Slope ($^{\circ}$)	System Noise (nm)
1X EPI	0.03	3.80	16891 x 14131	6,90	5,41	4,68	6,43	5,85	2	-
2.5X EPI	0.08	8.80	6756 x 5652	2,76	2,03	1,75	2,41	2,19	4	300
5X EPI	0.15	23.50	3378 x 2826	1,38	1,08	0,94	1,29	1,17	9	100
10X EPI	0.30	17.50	1689 x 1413	0,69	0,54	0,47	0,64	0,58	17	30
20X EPI	0.45	4.50	845 x 707	0,34	0,36	0,31	0,43	0,39	27	8
50X EPI	0.80	1.00	338 x 283	0,13	0,20	0,18	0,24	0,22	53	4
50X EPI	0.80	2.00	338 x 283	0,13	0,20	0,18	0,24	0,22	53	4
50X EPI	0.95	0.35	338 x 283	0,13	0,17	0,15	0,20	0,18	72	3
100X EPI	0.90	1.00	169 x 141	0,07	0,18	0,16	0,21	0,19	64	3
100X EPI	0.90	2.00	169 x 141	0,07	0,18	0,16	0,21	0,19	64	3
100X EPI	0.95	0.32	169 x 141	0,07	0,17	0,15	0,20	0,18	72	2
150X EPI	0.90	1.50	113 x 94	0,05	0,18	0,156	0,21	0,19	64	2
150X EPI	0.95	0.20	113 x 94	0,05	0,17	0,148	0,20	0,18	72	1
20X ELWD	0.40	19.00	845 x 707	0,34	0,41	0,35	0,48	0,44	24	10
50X ELWD	0.60	11.00	338 x 283	0,13	0,27	0,23	0,32	0,29	37	5
100X ELWD	0.80	4.50	169 x 141	0,07	0,20	0,18	0,24	0,22	53	3
10X SLWD	0.20	37.00	1689 x 1413	0,69	0,81	0,70	0,96	0,88	12	50
20X SLWD	0.30	30.00	845 x 707	0,35	0,54	0,47	0,64	0,58	17	20
50X SLWD	0.40	22.00	338 x 283	0,13	0,41	0,35	0,48	0,44	24	15
100X SLWD	0.60	10.00	169 x 141	0,07	0,27	0,23	0,32	0,29	37	10

The highest quality objective lenses,
the highest quality performance

Water immersion objective lenses

Magnification	NA	WD (mm)	FOV (μm)	Spatial Sampling (μm)	Optical Resolution Green (μm)	Optical Resolution Blue (μm)	Optical Resolution Red (μm)	Optical Resolution White (μm)	Maximum Slope ($^{\circ}$)
10X WI	0.30	3.50	1689 x 1413	0,69	0,54	0,47	0,64	0,58	17
20X WI	0.50	3.30	845 x 707	0,35	0,32	0,28	0,39	0,35	30
63X WI	1.00	2.00	268 x 224	0,11	0,16	0,14	0,19	0,18	90

Collar ring depth focusing correction objective lenses

Magnification	NA	WD (mm)	FOV (μm)	Spatial Sampling (μm)	Optical Resolution Green (μm)	Optical Resolution Blue (μm)	Optical Resolution Red (μm)	Optical Resolution White (μm)	Maximum Slope ($^{\circ}$)
20X EPI CR	0.45	10.9 – 10.0	845 x 707	0,35	0,36	0,31	0,43	0,39	27
50X EPI CR	0.70	3.9 – 3.0	338 x 283	0,138	0,23	0,20	0,28	0,25	44
100X EPI CRA	0.85	1.2 – 0.85	169 x 141	0,07	0,19	0,17	0,23	0,21	58
100X EPI CRB	0.85	1.3 – 0.95	169 x 141	0,07	0,19	0,17	0,23	0,21	58

Interferometry objective lenses

Magnification	NA	WD (mm)	FOV (μm)	Spatial Sampling (μm)	Optical Resolution Green (μm)	Optical Resolution Blue (μm)	Optical Resolution Red (μm)	Optical Resolution White (μm)	Maximum Slope ($^{\circ}$)
2.5X TI *	0.075	10.30	6756 x 5652	2,76	2,16	1,87	2,57	2,34	4
5X TI	0.13	9.30	3378 x 2826	1,38	1,25	1,08	1,48	1,35	7
10X DI	0.30	7.40	1689 x 1413	0,69	0,54	0,47	0,64	0,58	17
20X DI	0.40	4.70	845 x 707	0,35	0,41	0,35	0,48	0,44	24
50X DI	0.55	3.40	338 x 283	0,13	0,30	0,26	0,35	0,32	33
100X DI	0.70	2.00	169 x 141	0,07	0,23	0,20	0,28	0,25	44
Vertical resolution		PSI/ePSI 0.1 nm (0.01 nm with PZT *)					VSI 1 nm		



SENSOFAR is a leading-edge technology company that has the highest quality standards within the field of surface metrology

Sensofar Metrology provides high-accuracy optical profilers based on confocal, interferometry and focus variation techniques, from standard setups for R&D and quality inspection laboratories to complete non-contact metrology solutions for in-line production processes. The Sensofar Group has its headquarters in Barcelona, also known as a technology and innovation hub in Europe. The Group is represented in over 30 countries through a global network of partners and has its own offices in Asia, Germany and the United States.

HEADQUARTERS

SENSOFAR METROLOGY | BARCELONA (Spain) | T. +34 93 700 14 92 | info@sensofar.com

SALES OFFICES

SENSOFAR ASIA | SHANGHAI (China) | T. +86 021 51602735 | info.asia@sensofar.com

SENSOFAR GERMANY | MUNICH (Germany) | T. +49 151 14304168 | info.germany@sensofar.com

SENSOFAR USA | NEWINGTON (USA) | T. +1 617 678 4185 | info.usa@sensofar.com

sensofar.com